NAPSON CORPORATION

CALTRON PTE LTD

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NC-600MAP FULLY-AUTO SHEET RESISTANCE/ RESISTIVITY MEASUREMENT SYSTEM

NC-600MAP

- Fully automatic measurement system with one cassette station
- Multi-point, Non-Contact Type using Eddy current method
- Possible to measure wide range of sheet resistance by installing Maximum of 4 probes
- Minimum 7mm position from edge can be measured
- User programable measurement and measuring pattern
- Equipped with one cassette station (storage in the same slot after measurement)
- Option: Thickness measurement probe (for silicon wafer)
- Measure Range depends on selected Probe type
- Sample Size (Ø): 3” to 8”

MEASURE RANGE				
PARAMETER	LOW PROBE TYPE	MIDDLE PROBE TYPE	HIGH PROBE TYPE	S-HIGH PROBE TYPE
RESISTIVITY (Ω.cm)	0.001 to 0.05	0.05 to 0.5	0.5 to 60.0	60.0 to 200.0
SHEET RESISTANCE (Ω/Sq)	0.01 to 0.5	0.5 to 10.0	10.0 to 1k	1k to 3k

APPLICABLE MATERIALS

- Semiconductor and Solar-cell materials (Silicon, Polysilicon, SiC etc)
- Conductive thin film (Metal, ITO etc)
- Diffused sample (or layer)
- Silicon-related epitaxial materials
- Ion-implantation sample
- Others: On Request

All images are for illustration purposes only. Actual product may differ.